

**Device and method for drying and/or cleaning pot-shaped hollow
bodies, in particular transport containers for semiconductor
wafers or for EUV lithography masks**

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Abstract

The present invention relates to a device (10) for drying
and/or cleaning pot-shaped hollow bodies (12), in particular
transport containers for semiconductor wafers or for EUV
10 lithography masks, wherein the hollow body (12) has a hollow
body wall (14) that forms an inner hollow body surface (16),
with the inner hollow body surface (16) bounding an inner
hollow body space (17), and a hollow body opening (18) that is
surrounded by the hollow body wall (14) and through which the
15 inner hollow body space (17) is accessible, with the device
(10) comprising a first holding means (30) by which the device
(10) can interact with the hollow body wall (14) in a holding
manner, an evacuation device (60) for applying a vacuum in the
inner hollow body space (17) and/or a conveying device (66)
20 for conveying a flushing fluid through the inner hollow body
space (17), and a displacement member (48) that can be or is
introduced into the inner hollow body space (17) through the
hollow body opening (18). The invention further relates to a
corresponding method of drying and/or cleaning pot-shaped
25 hollow bodies (12).

(Figure 1E)